

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Thomas Hecht et al.	Examiner:	Unknown								
erial No.:	10/529,412	Group Art Unit:	1762								
iled:	December 21, 2006	Docket No.:	1433.153.101/13.555								
itle:	METHOD AND PROCESS REACTOR FOR SEQUENTIAL GAS PHASE DEPOSITION BY MEANS OF A PROCESS CHAMBER AND AN AUXILARY CHAMBER										
ommission 2.O. Box 14	mendment ner for Patents 50 VA 22313-1450										
ir:											
Ve are tran	smitting herewith the attached	d:									
✓ Transm	nittal Sheet containing Certifica	ate of Mailing under 37 C.F.R.	1.8								
Supplemental Information Disclosure Statement 2 pg(s).											
K Form P	TO-1449 <u>1</u> pg(s).										
✓ Copy of	f 2 cited references		-								
The Co	ommissioner is authorized to cl	harge <b>\$0.00</b> to Deposit Ac	count No. 500471 to cover the required fee.								
Other:											
⊠ Return	Postcard	War									
	Customer No. 025281	By Name: Paul P. Kempf (Reg. No	p. 39,727)								
Please cons	ider this a Petition for Extension of Time	e for a sufficient number of months to	p enter these papers, if appropriate. At any time								

Please consider this a Petition for Extension of Time for a sufficient number of months to enter these papers, if appropriate. At any time during the pendency of this application, please change any additional fees or credit overpayment to Deposit Account No. 500471.

CERTIFICATE UNDER 37 C.F.R. 1.8:  Date of Deposit: $930507$	_
The undersigned hereby certifies that this paper or pa United States Postal Service as First Class Mail, address Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	_ ·



## <u>IN THE UNITED STATES PATENT AND TRADEMARK OFFICE</u>

Applicant: Thomas Hecht et al.

Examiner: Unassigned

Serial No.:

10/529,412

Group Art Unit: 1762

Filed:

December 21, 2006

Docket: I433.153.101/13.555

Title:

METHOD AND PROCESS REACTOR FOR SEQUENTIAL GAS PHASE

DEPOSITION BY MEANS OF A PROCESS CHAMBER AND AN

**AUXILARY CHAMBER** 

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

Dear Sir/Madam:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Supplemental Information Disclosure Statement be entered and the documents listed on attached form 1449 be considered by the Examiner and made of record. The cited references are enclosed for the Examiner's review. Pursuant to the provisions of M.P.E.P. 609, Applicants further request a copy of the 1449 form, marked as being considered and initialled by the Examiner, be returned with the next Official Communication.

Since this Supplemental Information Disclosure Statement is being submitted within three months of filing national application; or date of entry of national application; or before the mailing date of the first Office Action on the merits, a fee has not been enclosed. However, if such fee is required, the Patent Office is hereby authorized to charge Deposit Account No. 500471 for fees as set forth under 37 C.F.R. 1.17(p).

**Supplemental Information Disclosure Statement** 

Applicant: Thomas Hecht et al. Serial No.: 10/529,412 Filed: December 21, 2005

Docket No.: 1433.153.101/13.555

Title: METHOD AND PROCESS REACTOR FOR SEQUENTIAL GAS PHASE DEPOSITION BY MEANS OF A PROCESS

CHAMBER AND AN AUXILIARY CHAMBER

Applicants respectfully request consideration of these references during prosecution of the above-identified matter. The Examiner is invited to contact the Applicants' representative at the below-listed telephone number if there are any questions regarding this Communication or the tendered references.

Respectfully submitted,

Thomas Hecht et al.

By their attorneys,

DICKE, BILLIG & CZAJA, PLLC Fifth Street Towers, Suite 2250 100 South Fifth Street Minneapolis, MN 55402

Telephone: (612) 767-2502 Facsimile: (612) 573-2005

Dated: <u>03/0≤/07</u>

PPK/mlm

Paul P. Kempf

Reg. No. 39,727

CERTIFICATE UNDER 37 C.F.R. 1.8: The undersigned hereby certifies that this paper or papers, as described herein, are being deposited in the United States Postal Service, as first class mail, in an envelope address to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on this 4 day of 4 day

Name: Paul P. Kempf

FORM PEO				D. L. N	1422 152 101		G : 1N 10/500 440
FORM PTO-1449				Docket No.: 1433.153.101/13.555   Serial No.: 10/529,412			
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S				Applicant: Thomas Hecht et al.			
INFORMATION DISCLOSURE STATEMENT				Filing Date:	December 2	Group Art: 1762	
MAR 0 8 200		U.S. 1	PATENT DO	CUMENTS			
Examiner Document No. Initial		Date		ne	Class	Sub Class	Filing Date If Appropriate
AA							
AB							
AC							
AD							
AE							
AF							
AG							
AH							
AI							
AJ							
AK							
AL							
		FOREIG	N PATENT	DOCUMENTS	3		
	Document No.	Date	Co	ountry	Class	Sub Class	Translated Yes No
AM	1 446 262	03/05/1970	Germany				Yes (Abstract)
AN	44 01 718	08/18/1995	Germany				Yes (Abstract)
AO							Yes
	OTH	HER ART (Includin	g Author, Tit	le, Date, Pertin	nent Pages, Et	c.)	
AR							
AS							
AT							

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

EXAMINER:

DATE CONSIDERED: